

Patent Application No. 10/791,014

Customer Number: 42717

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicant: Chung-Shi Liu, et al. Serial No.: 10/791,014 Filing Date:

Examiner:

Fetsum Abraham

(TSMC2000-0488)

24061.596

March 2, 2004

Art Unit:

Docket No.:

2826

For:

Prevention of Post CMP Defects in CU/FSG Process

Conf. No.:

1306

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop: Amendment Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed March 22, 2005, applicant hereby elects, Group II, Claims 35-44, which is drawn to a method of making a semiconductor device.

Applicant's election is made with traverse on the grounds that the embodiments delineated by the examiner are not patentably distinct and therefore constitute a single invention concept.

An early action on the merits is respectfully requested.

Respectfully submitted,

Wei Wei Jeang

Reg. No. 33,305

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop: Amendment, Commissioner For Patents, PO Box 1450, Alexandria, VA 22313-1450 on the date below.

Name

Date